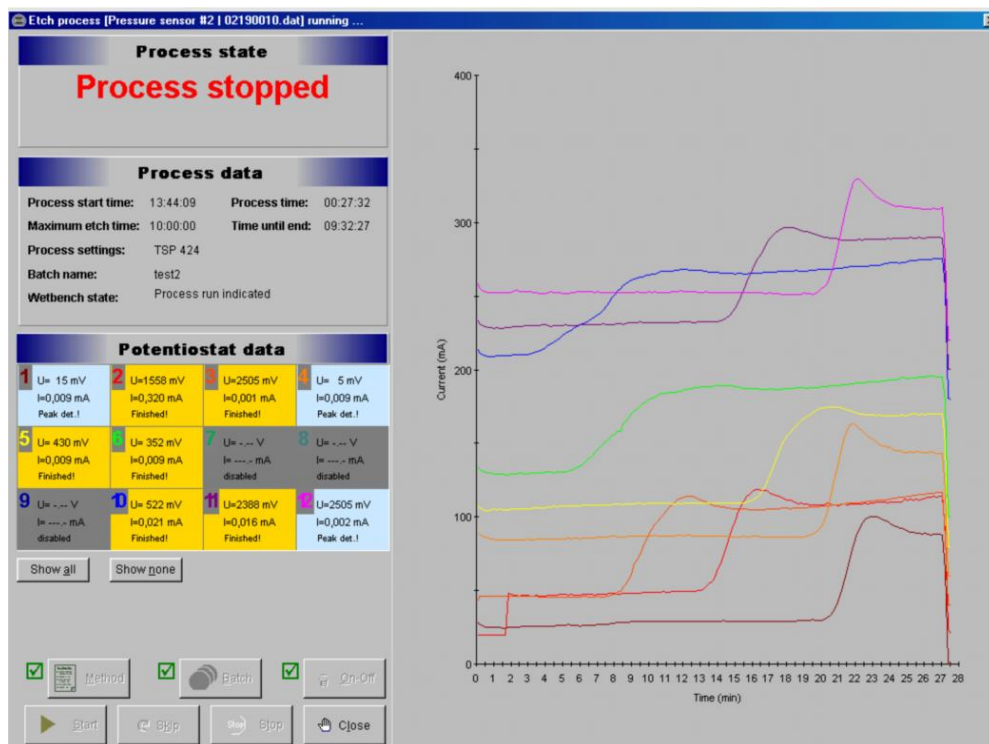


Etch Process Control Software (EPC)

for Windows 95/98, NT/2000 and XP

AMMT's control software for the MEMS Potentiostat Models SC and MC is a versatile software package developed for development and production environments that operates up to 16 potentiostats in parallel. The software allows:

- to control all features of AMMT's MEMS Potentiostats,
- define process methods, store and retrieve them,
- run and follow processes on EPC's graphical user interface,
- access each potentiostat's process values, even down to its internal supply voltages,
- follow the etch process in your office over your computer network via our remote control features,
- save all process relevant data for each batch for later use and inspection,
- print summarized or detailed reports on each etch process for documentation purposes,
- increase your yield with the MEMS Potentiostat's error detection mechanism that warns you early in case of problems (etchant leak, broken wafer or cable failure)
- use the potentiostat peak detection feature to alert you when the process is finished
- start an external system to rinse the wafers or transfer them to a different bath



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